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In re Application of:

Kiyoshi ARAKAWA

Application No.: 10/622,143

Filed: July 18, 2003

For: EXPOSURE APPARATUS, MAINTENANCE
METHOD THEREFOR, SEMICONDUCTOR
DEVICE MANUFACTURING METHOD
USING THE APPARATUS, AND
SEMICONDUCTOR MANUFACTURING
FACTORY

Examiner: H. Nguyen

Group Art Unit: 2851

Confirmation No.: 1879

October 7, 2004

Mail Stop Amendment

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

Transmitted herewith is an Amendment in the above-identified application.

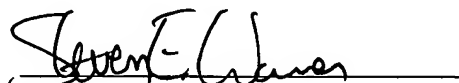
☐ No additional fee is required.

The fee has been calculated as shown below:

Page 1 of 2

- ☐ °Verified Statement claiming small entity status is enclosed, if not filed previously.
- ☐ A check in the amount of \$_____ is enclosed.
- ☐ Charge \$____ to Deposit Account No. 06-1205. A duplicate of this sheet is enclosed.
- ☒ Any prior general authorization to charge an issue fee under 37 CFR 1.18 to Deposit Account No. 06-1205 is hereby revoked. The Commissioner is hereby authorized to charge any additional fees under 37 CFR 1.16 and 1.17 which may be required during the entire pendency of this application, or to credit any overpayment, to Deposit Account No. 06-1205. A duplicate of this paper is enclosed.
- ☐ A check in the amount of \$_____ to cover the fee for a _____ month extension is enclosed.
- ☐ A check in the amount of \$_____ to cover the Information Disclosure Statement fee is enclosed.
- ☒ Applicant's undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should be directed to our address given below.

Respectfully submitted,



Attorney for Applicant
Steven E. Warner
Registration No. 33,326

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SEW/eab

DC_MAIN 180550v1



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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	
	:	Examiner: H. Nguyen
Kiyoshi ARAKAWA)	
	:	Group Art Unit: 2851
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FACTORY	:	

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Sir:

In response to the Official Action dated July 7, 2004, please amend the above-identified application as follows: